

Development and R2R Scale up of a Hybrid Printed CMOS Silicon TFT Process

Patricia Beck
Principal Engineer

Thin Film Electronics ASA

1

Near Field
Communications (NFC)
for IoT enablement

2

Global leader in printed
electronics

3

Scaling to the billion of
units by roll based
manufacturing



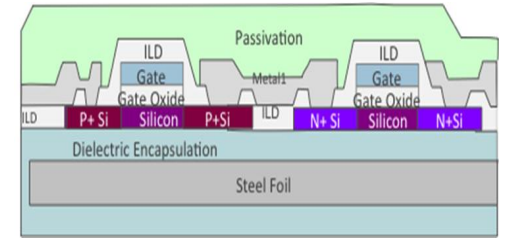
- Publicly listed OSE/OTCQX
- Over 290 patents and patents-pending printed electronics & NFC (near field communication)
 - Award-winning NFC Innovation Center in Silicon Valley
 - Broad & diverse global partner ecosystem

Outline

IoT of Everyday Objects using Near Field Communication (NFC)



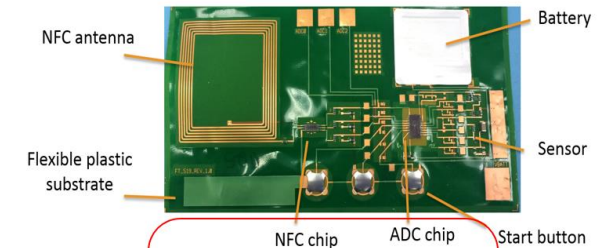
CMOS Silicon TFT with Silicon on Stainless Steel Substrate



Volume Scaling to Low Cost with Roll Processing



Product Evolution with Sensors



Thinfilm's Vision

Add a
little bit
of intelligence



to *a lot* of things.

Near Field Communication (NFC):



Instant launch of
brew master video

Single Bit Open/Closed Sensor

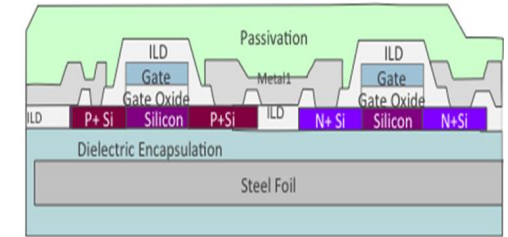


Outline

IoT of Everyday Objects using Near Field Communication (NFC)



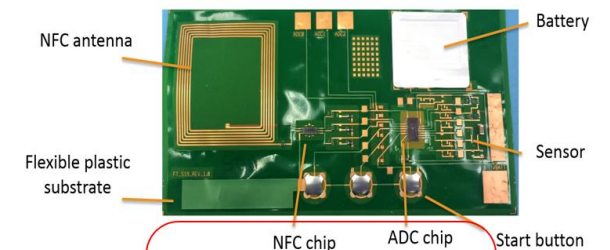
CMOS Silicon TFT with Silicon on Stainless Steel Substrate



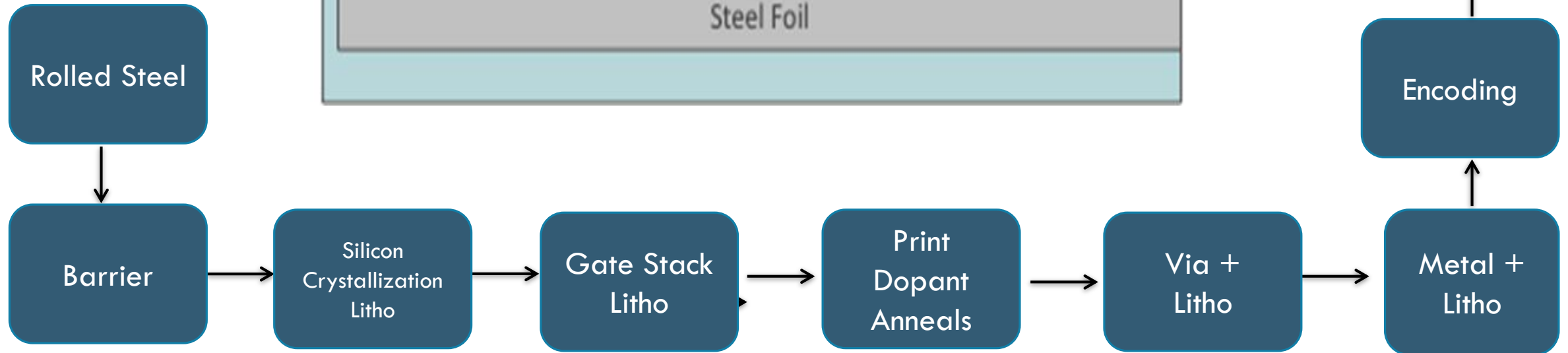
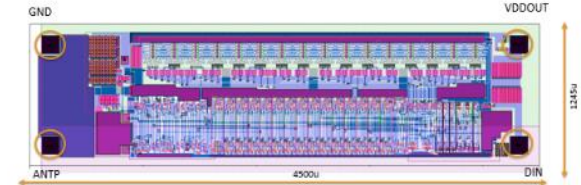
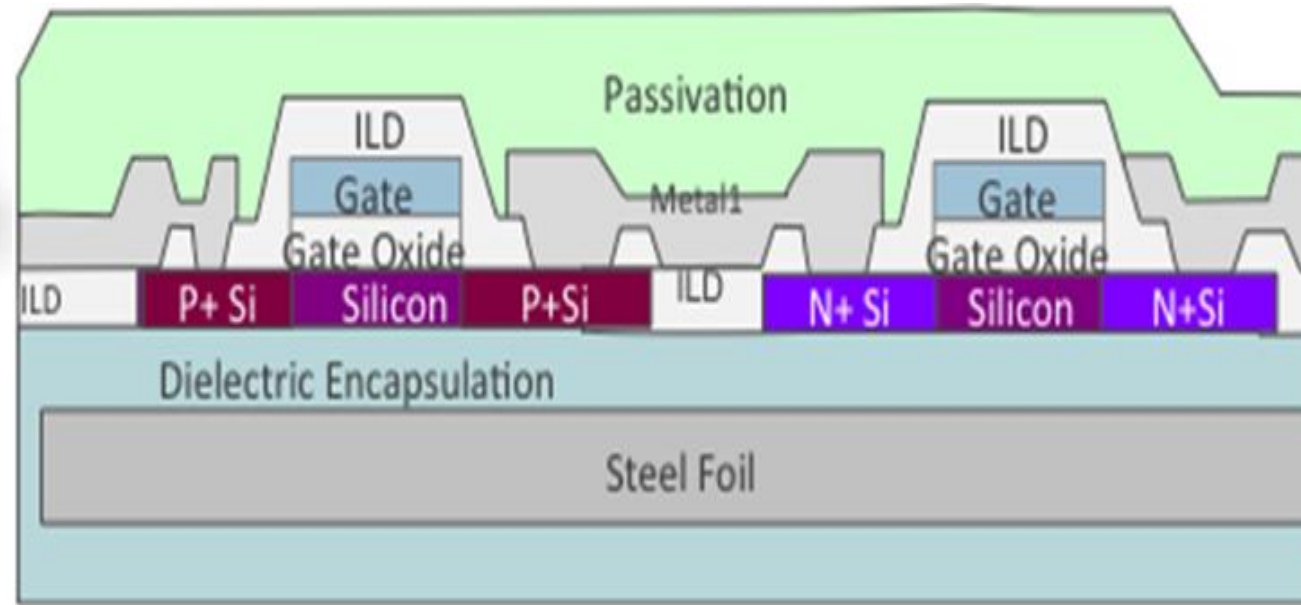
Volume Scaling to Low Cost with Roll Processing



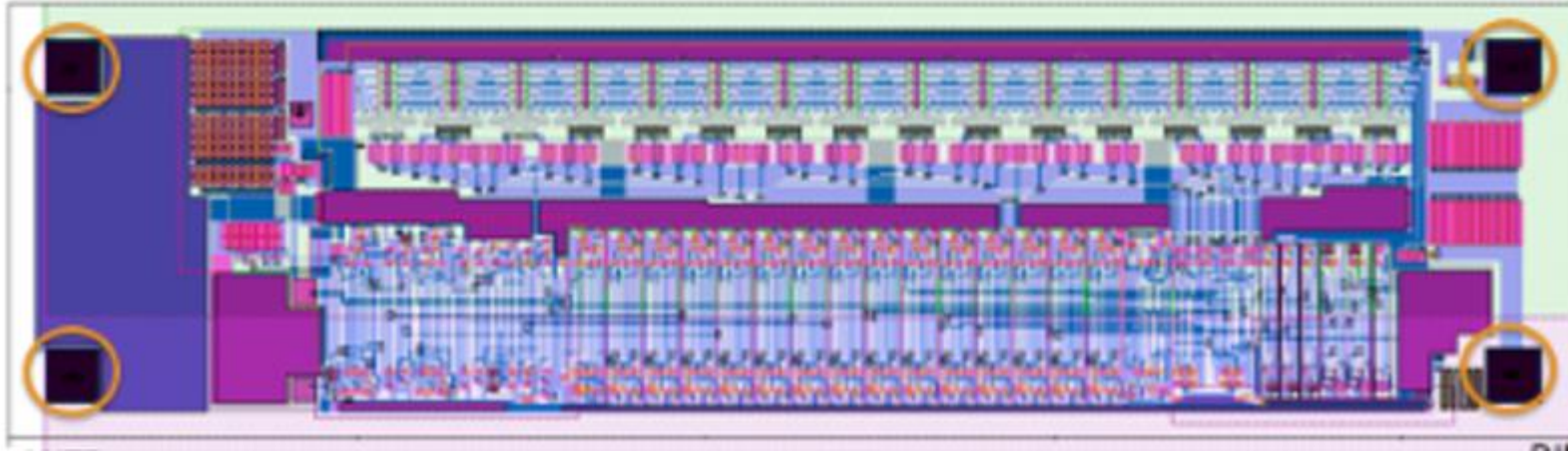
Product Evolution with Sensors



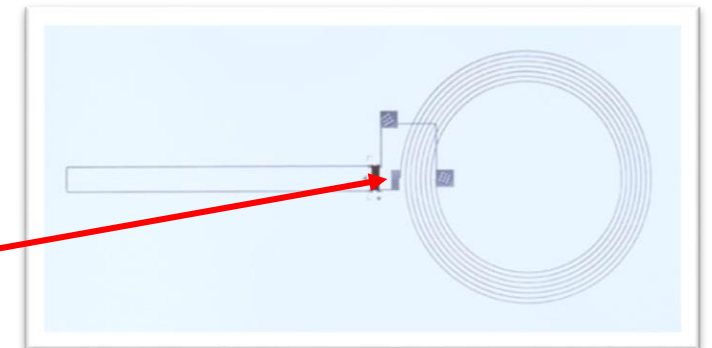
Printed Dopant CMOS Poly-TFT Process on Stainless Steel Foil



128 Bit CMOS NFC



- 13.56 MHz Operation
- 128 Bit ROM (cannot be rewritten)
- Tags Talk First Protocol: 5ms Read Times
- Adequate Area for Interface to Sensor Pads
- Optimized Die Size for Low Cost Attach to Antenna

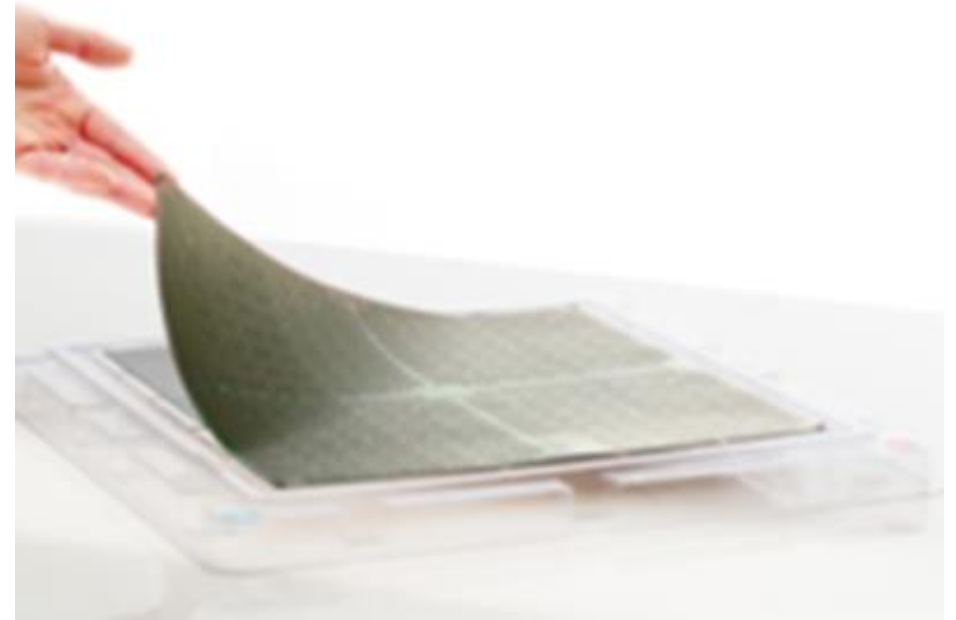


Key Technology Requirements

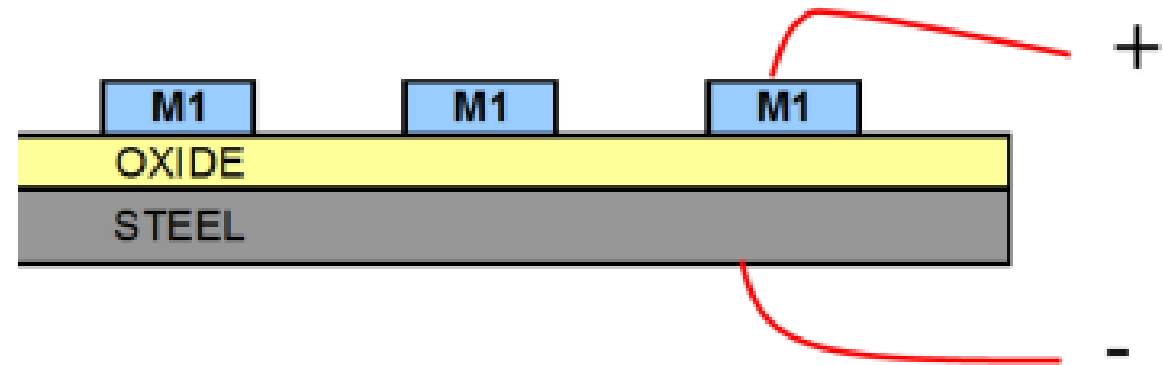
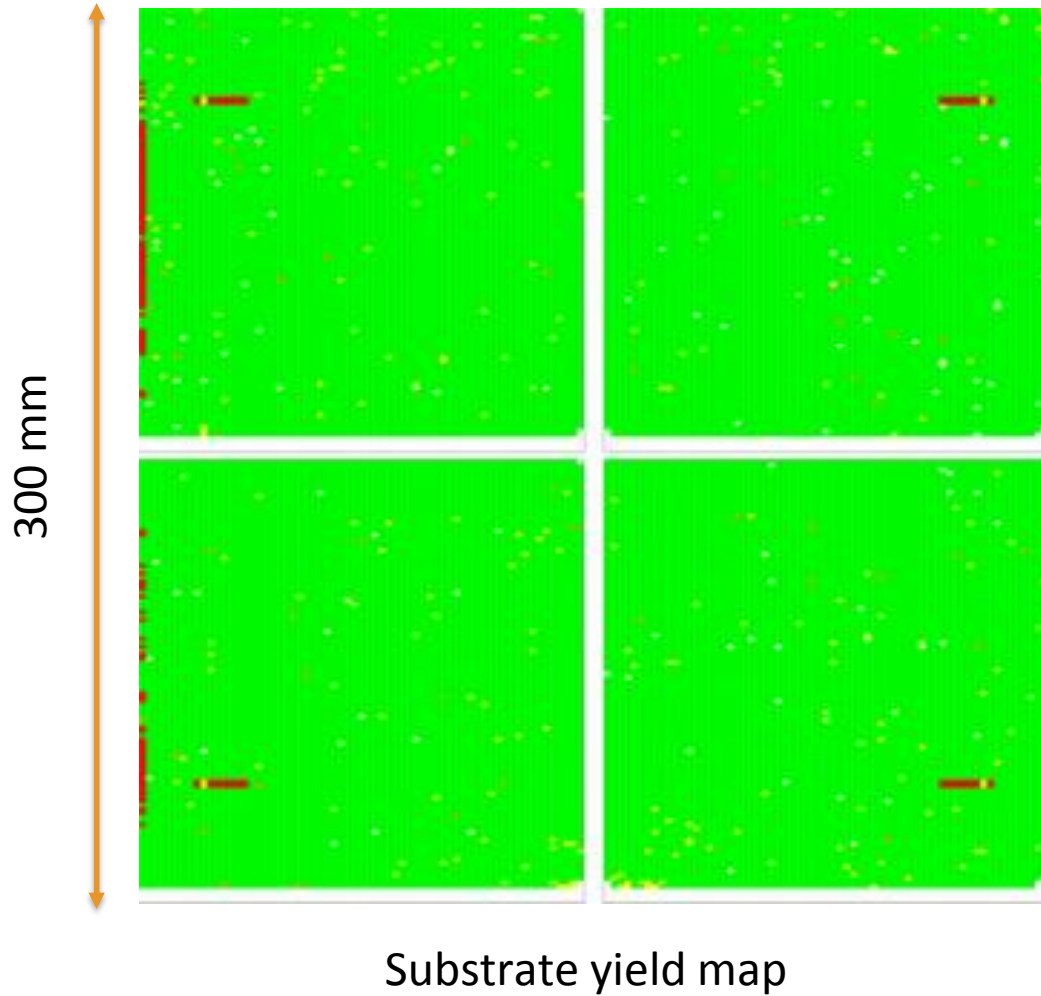
- Low Cost, Low Step-Count TFT based Roll-to-Roll Manufacturing
 - Billions - trillions of low cost units at scale
 - *R2R compatible process and assembly*
 - Roadmap to lowest step-count and capital cost
 - *Maximize print content with excellent overlay capability*
 - *Hybrid processing (lithography) where print cannot yet support critical design rules*
- RF (13.56 MHz) Capable Circuits and Materials
 - High mobility, low power circuits with adequate transistor density
 - *Self-aligned top-gate CMOS*
 - *Laser crystalized, polysilicon based TFT*
 - Thin, unbreakable form factor with low cost and excellent dimensional stability
 - *100um Stainless steel substrate with a roadmap to <50um*
 - *No need for backgrind and thinning*
 - *Printed semiconductor-grade inks and films (silicon and dopants)*

Stainless Steel Substrate: Key Advantages

- Low Cost
- Large Area, Thin, Unbreakable Form Factor
- High Reflectivity and Smoothness
 - *Polished Surface* <20um flatness
- Compatible with Dicing and Assembly Processes
- Scalable to Roll Format
 - *Dimensional Stability*
 - *High Temperature Compatible*
 - *High Quality Diffusion Barrier*



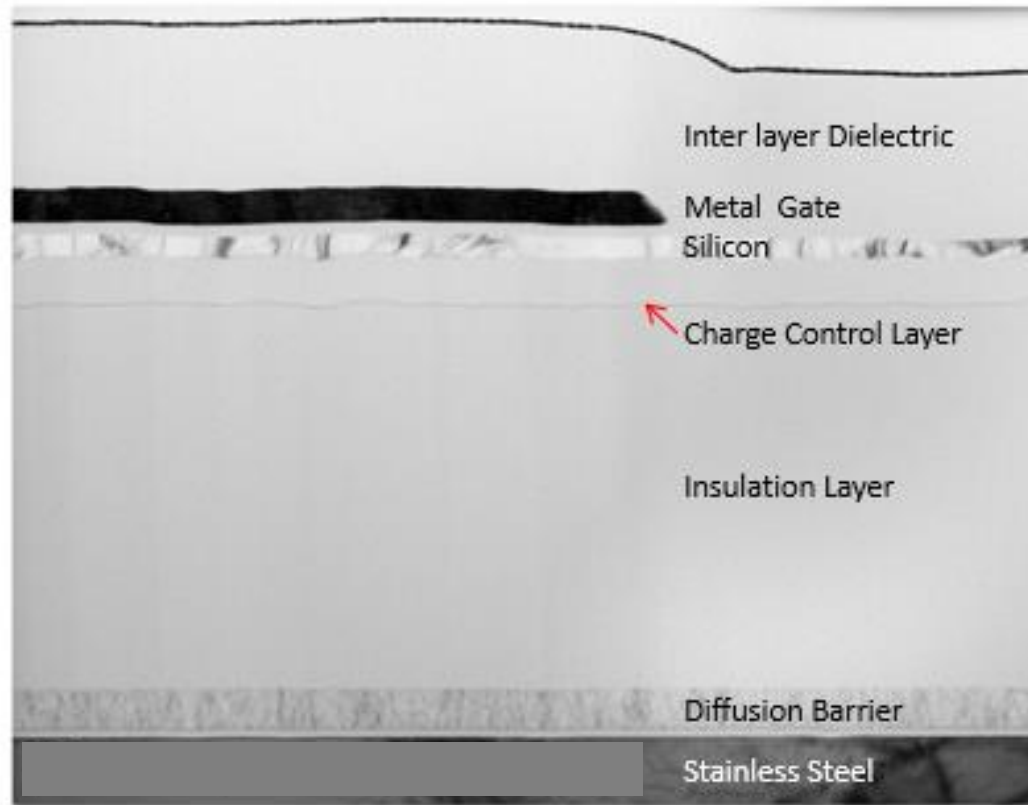
Stainless Steel Substrate: Defectivity



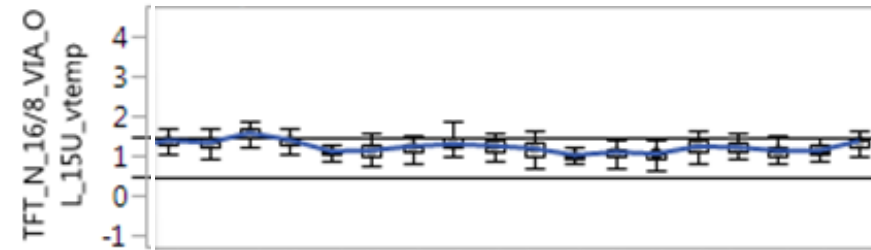
Schematic cross section of MIM capacitors (not to scale)

- Green die represent tens of thousands of yielding capacitors tested at voltages up to tens of volts
- Individual capacitor areas are several mm² with negligible substrate shorts
- **Substrate roughness is not a concern in terms of product yield!**

Vt and Charge Control



PDPS Transistor (TFT) Stack



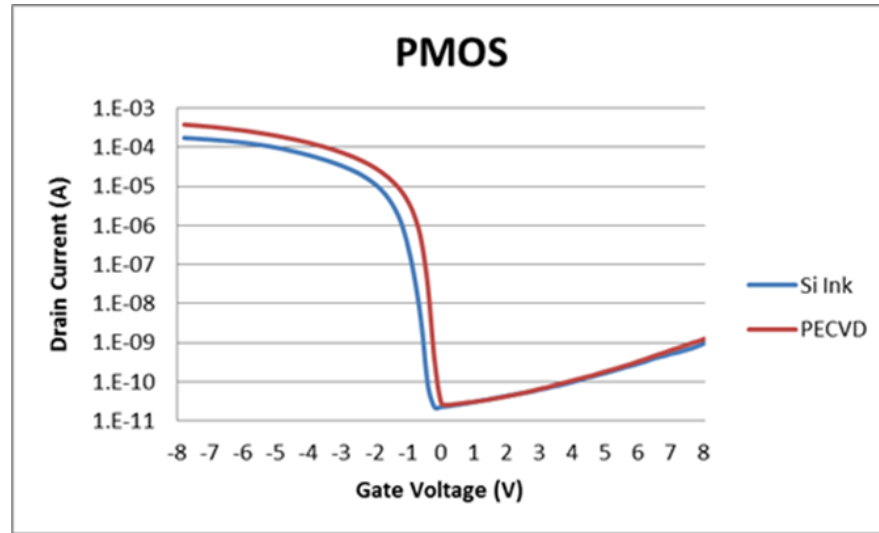
NMOS lot-to-lot Vt variation (volts)

Ten 300 x 300 mm sheets/lot

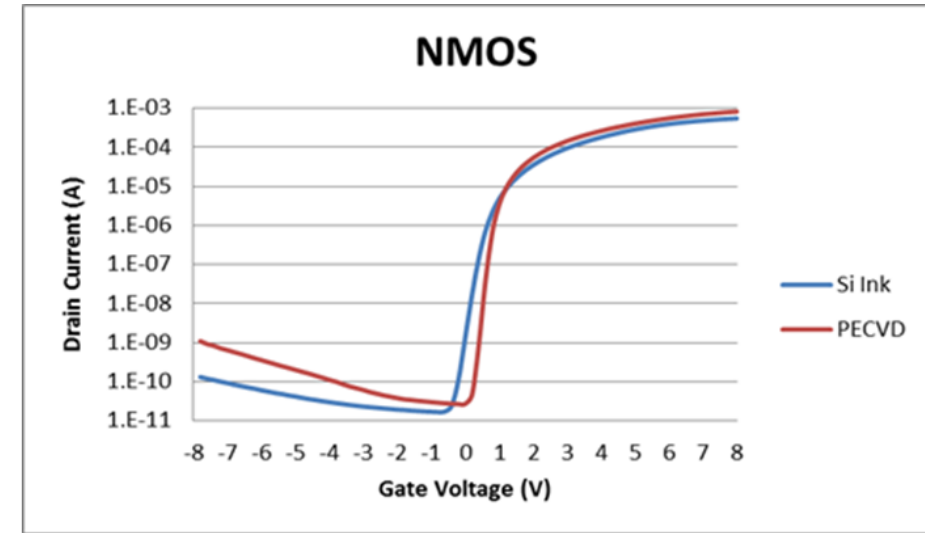
No Vt adjust ion implantation is used in the PDPS process flow.

Manufacturing Vt Control and targeting achieved using stack and device parameter engineering

TFT Characteristics: PECVD vs Liquid Silicon Ink



Id-Vg characteristics of PMOS TFT devices prepared with ink-based and PECVD methods. W/L = 8 μ m/4 μ m



Id-Vg characteristics of NMOS TFT devices prepared with ink-based and PECVD methods. W/L = 8 μ m/4 μ m

Typical TFT Parameters of PECVD and ink-based transistors with printed dopant on 300mm x300mm stainless steel substrate.

TFT type	PMOS		NMOS	
Film Deposition method	PECVD	Ink	PECVD	Ink
Mobility sat [cm ² /Vs]	80	80	200	200
Threshold Voltage[V]	-0.6	-0.9	1.0	1.0
Slope [V/decade]	0.25	0.25	0.25	0.25
On/Off	1.00E+07	1.00E+07	1.00E+07	1.00E+07

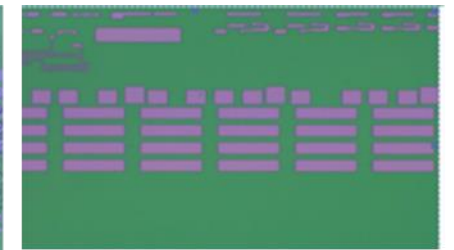
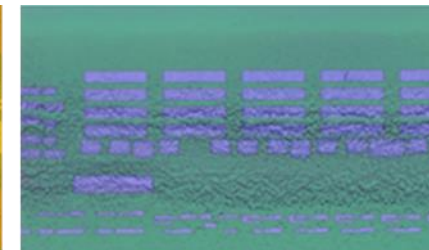
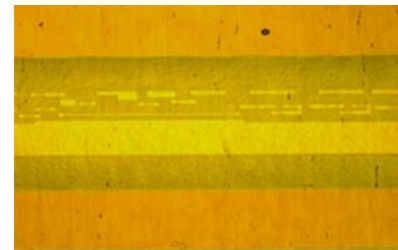
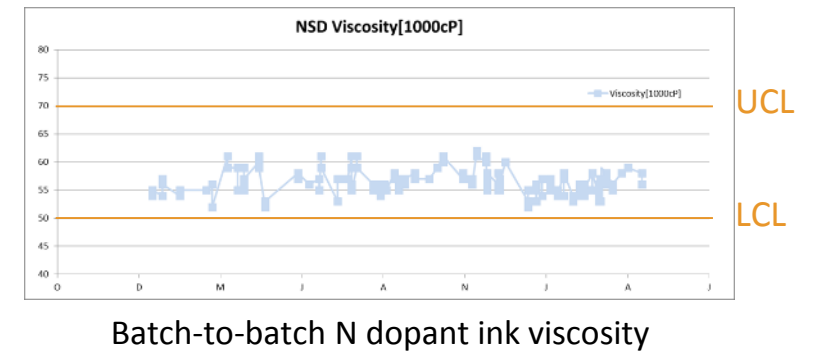
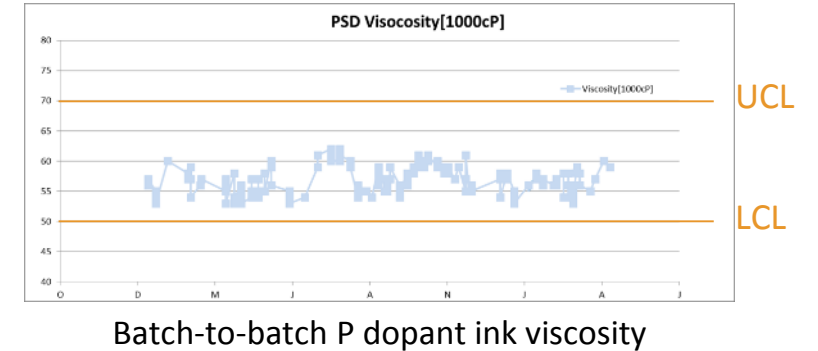
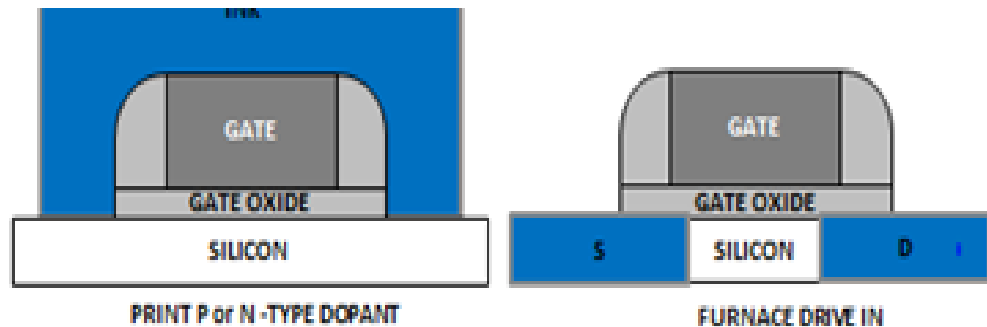
Screen Printed N and P Dopants: No ion implant

Key Printed CMOS Enabling Technology

- Low maintenance, high throughput, low step count module.
- Eliminates High capex Ion Implantation and Lithography
- *Potentially Applicable to c-silicon solar process*

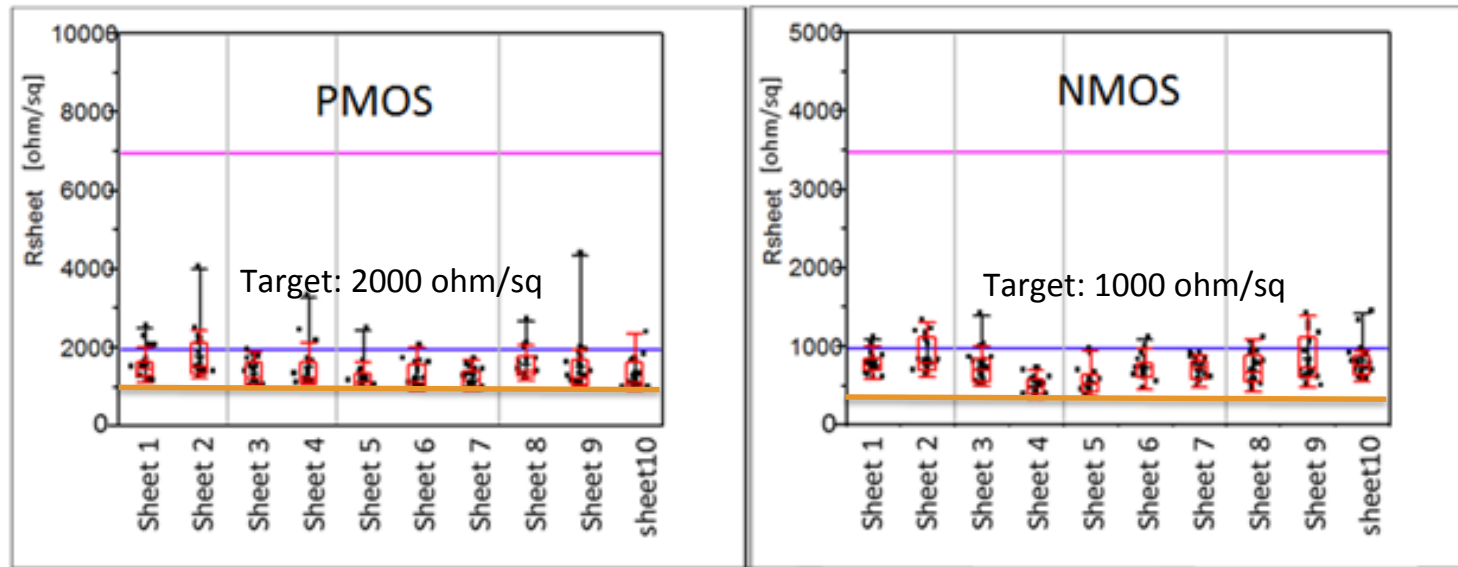
Ink Formulation and Printing Process

- Semiconductor grade purity
- Excellent batch viscosity control in a manufacturing environment

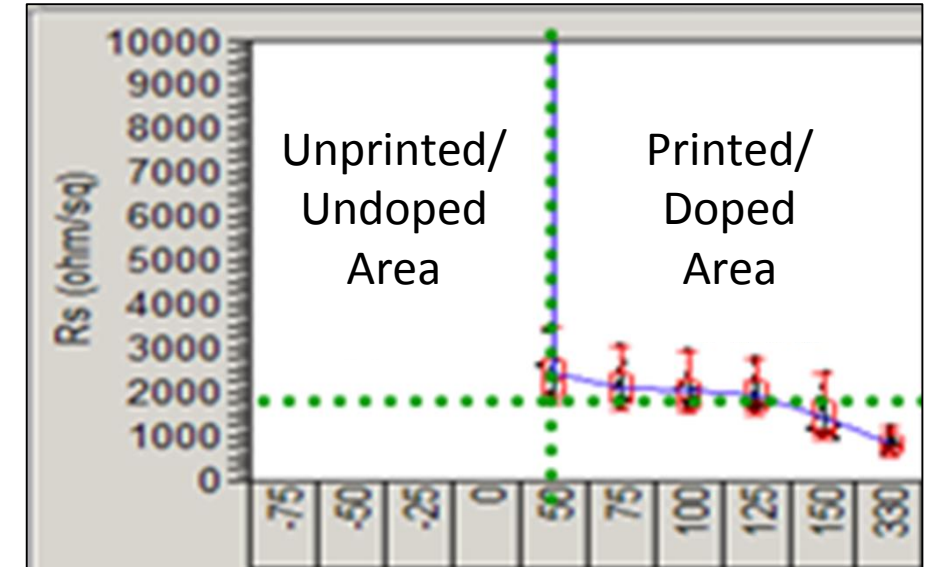


Doping Control

- Tight silicon sheet resistance (R_s) distributions (thermally activated).
- R_s can be targeted from 200-2000 ohm/square based on surface engineering, ink formulation and activation method.
- Highly Selective Doping. N and P doped areas can abut limited only by print resolution.



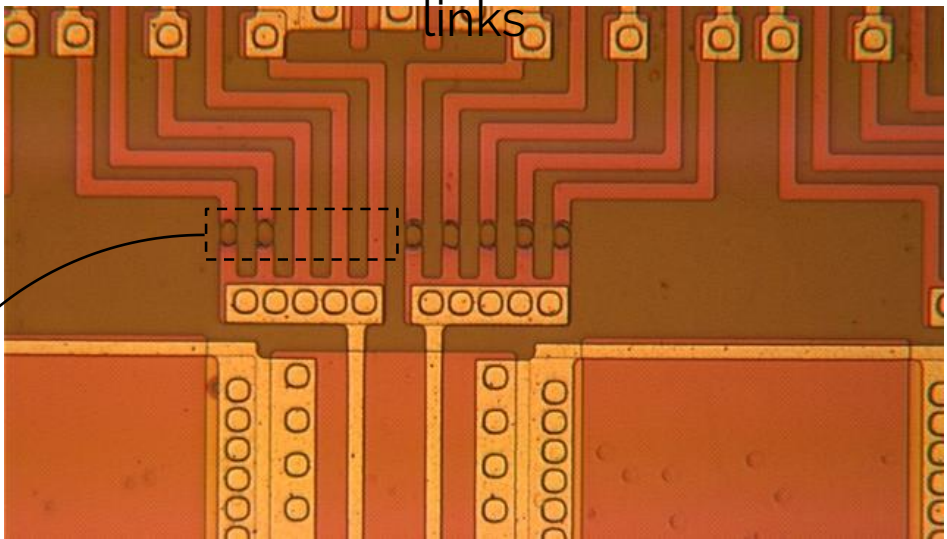
Sheet resistance distributions within a lot of 10 sheets. R_s values for P+ and N+ doped resistors.



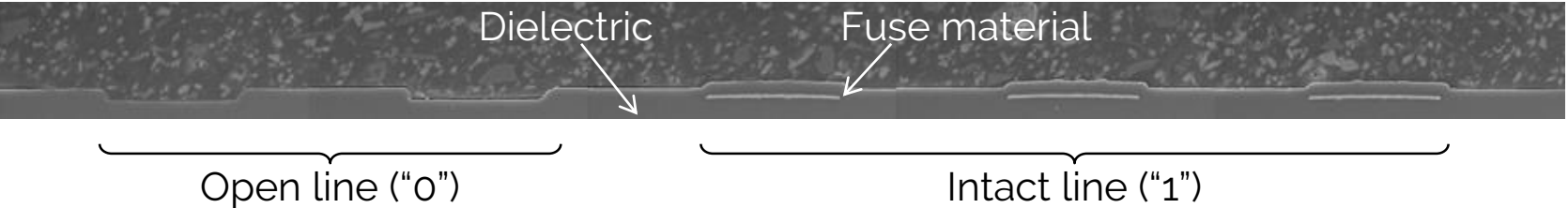
Location dependent doping. The "0" mark is at the edge of the printed dopant area. The x-axis unit is microns.

Encoded Read Only Memory

Top view of open ("0") and intact ("1") fuse links

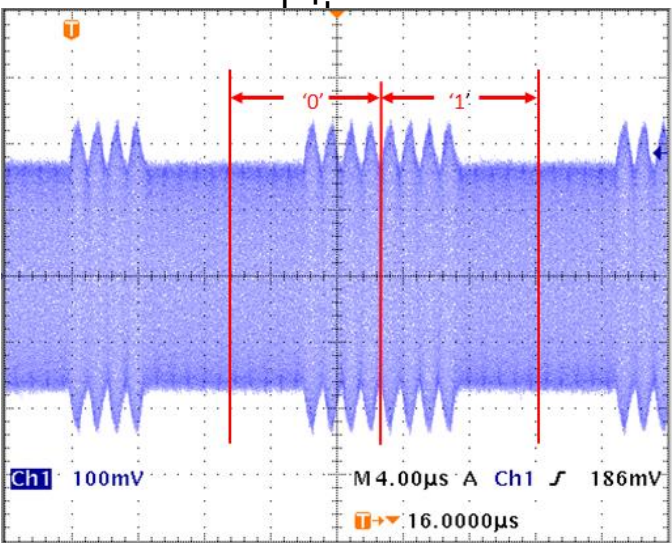


Preferentially ablated material produces a reliable open state



Cross section of encoded fuses

Oscilloscope Readout of "0" and "1"

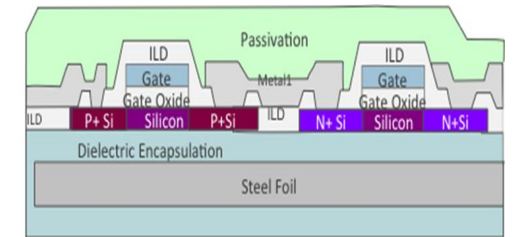


Laser Encoding is key to a factory programmed, unalterable NFC 128 bit code

IoT of Everyday Objects using Near Field Communication (NFC)



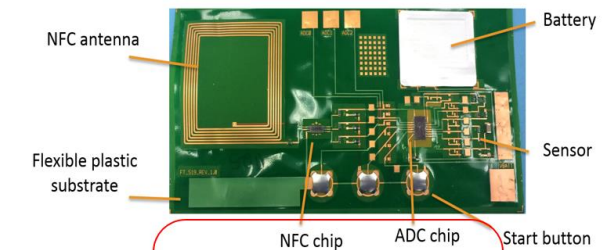
CMOS Silicon TFT with Silicon on Stainless Steel Substrate



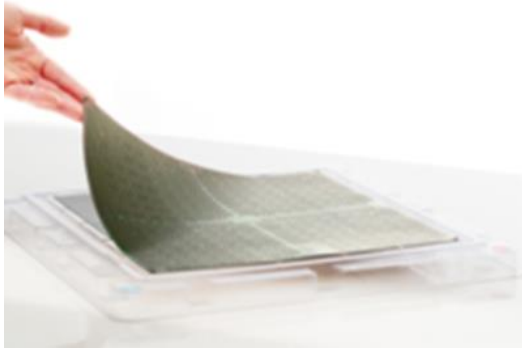
Volume Scaling to Low Cost with Roll Processing



Product Evolution with Sensors



Scale up



300 mm x 300 mm

320 mm x 200 meters

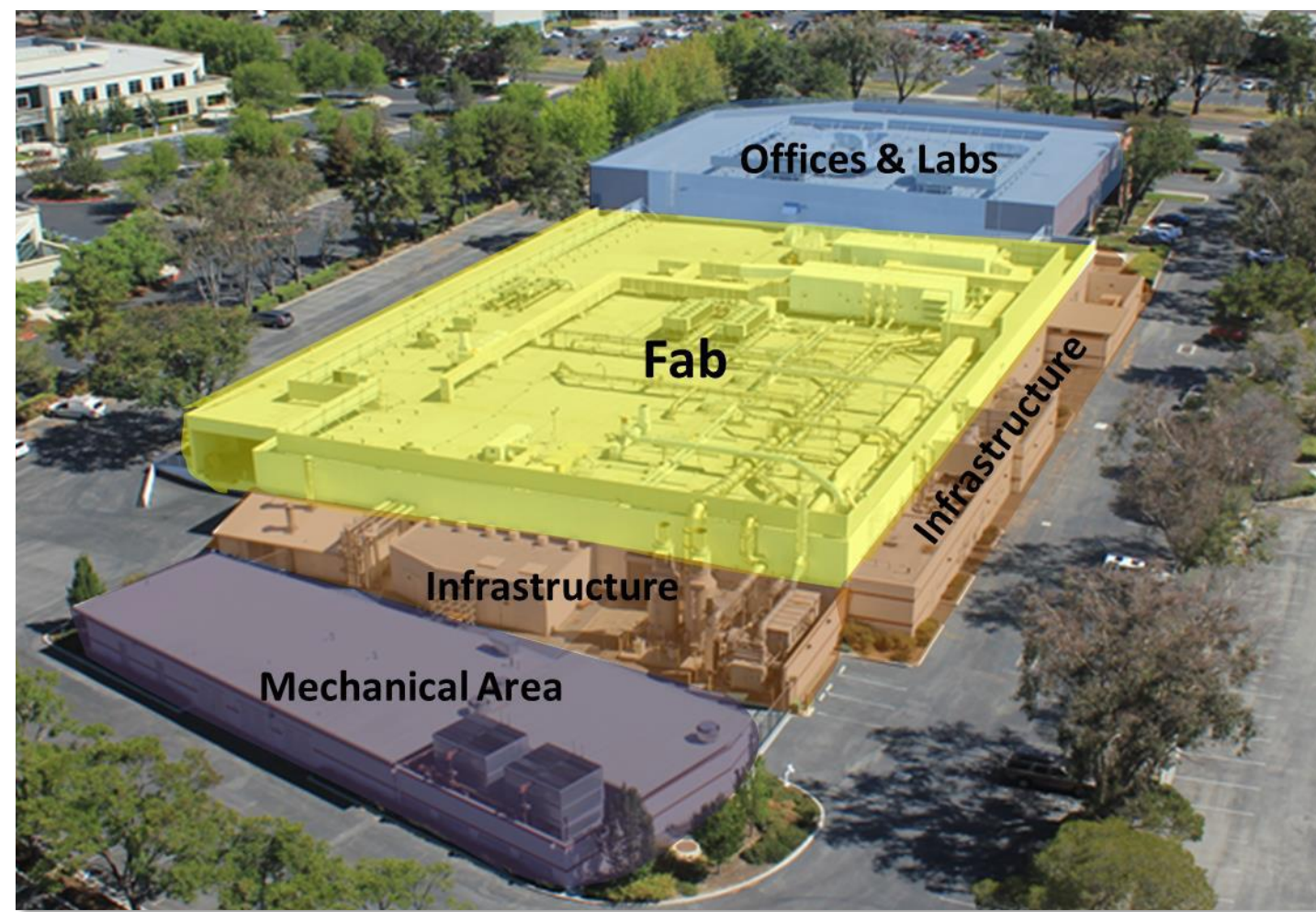
100 μm thick

75 to 50 μm

10s of Millions

Billions

Scaling to Billion-Unit Volumes for EAS and NFC in new facility using R2R manufacturing



2581 Junction Avenue, San Jose, California

Scaling to Billion-Unit Volumes

Roll-to-Roll Unit Operations

- Up to 7 billion unit NFC annual capacity (SpeedTap™ / OpenSense™)
- 320mm wide steel web
- Discrete process modules combining print and lithography where appropriate
- Total front-end die cost reduced by 10x, material dominated



Ultra Scale R2R Processing



Vacuum



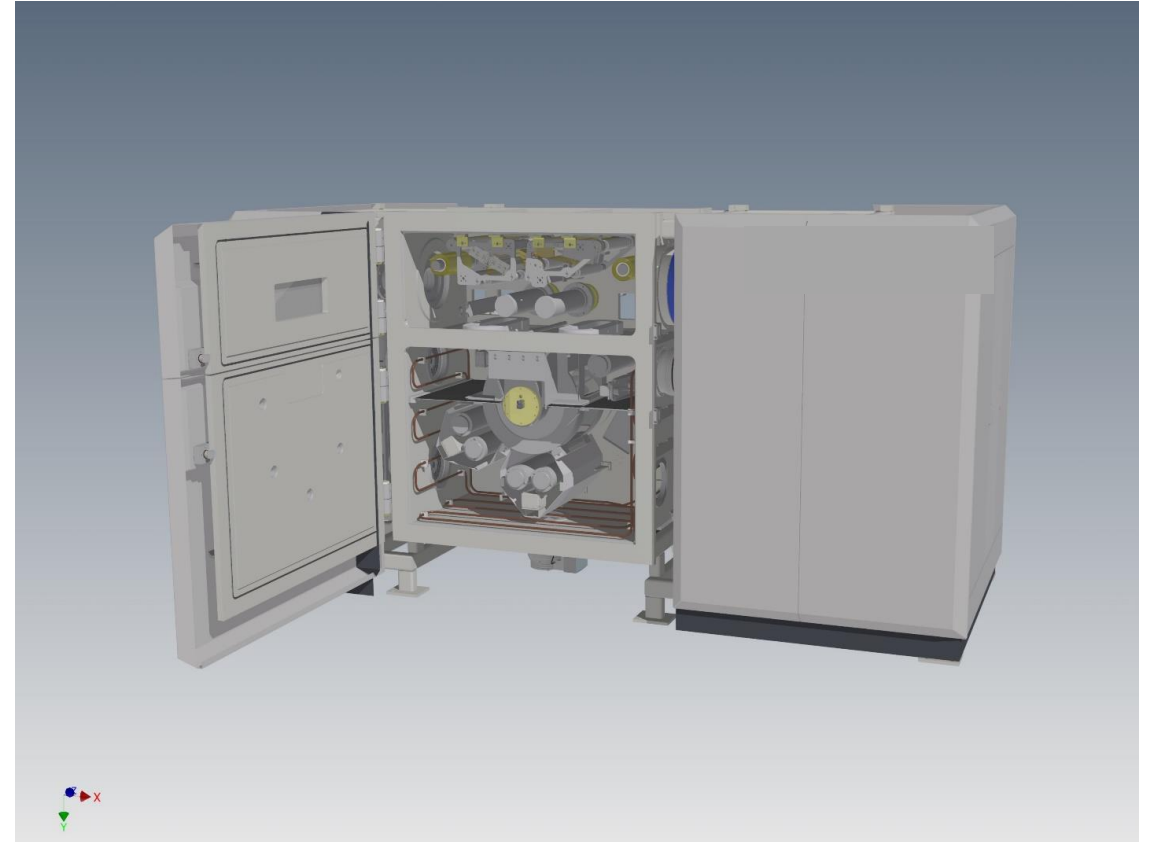
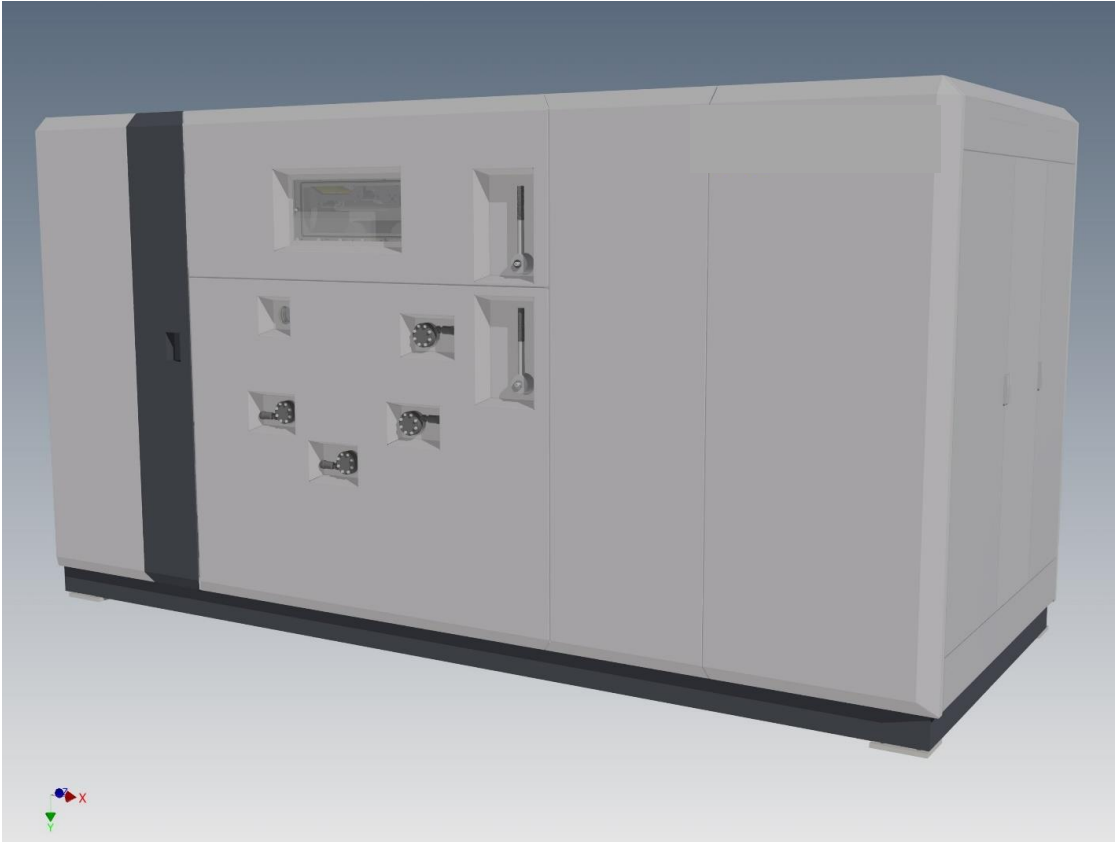
15 Toolsets including Metrology and Test
In various stages of install and build



Litho



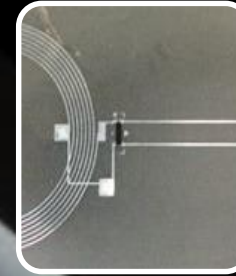
Example: Modular Metal Sputter Tool



Three materials are run in one tool without re-tooling.

Roll-to-Roll Flow in Backend - Inlay Manufacturing

Attach



Conversion



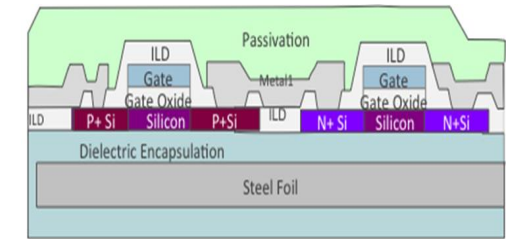
Test



IoT of Everyday Objects using Near Field Communication (NFC)



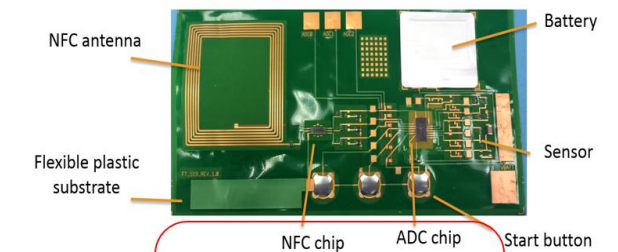
CMOS Silicon TFT with Silicon on Stainless Steel Substrate



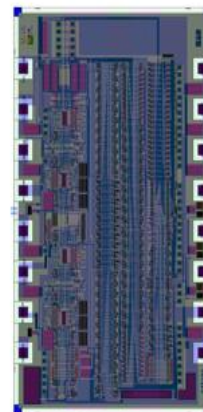
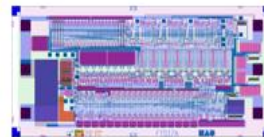
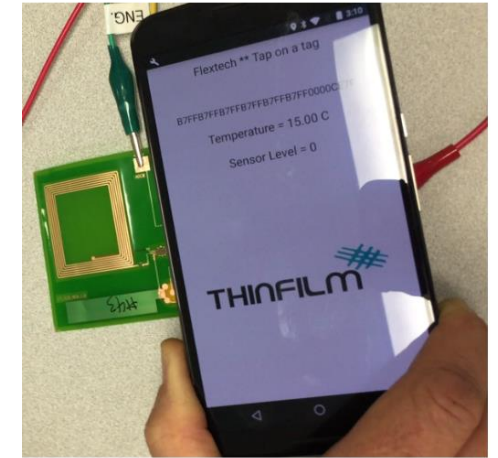
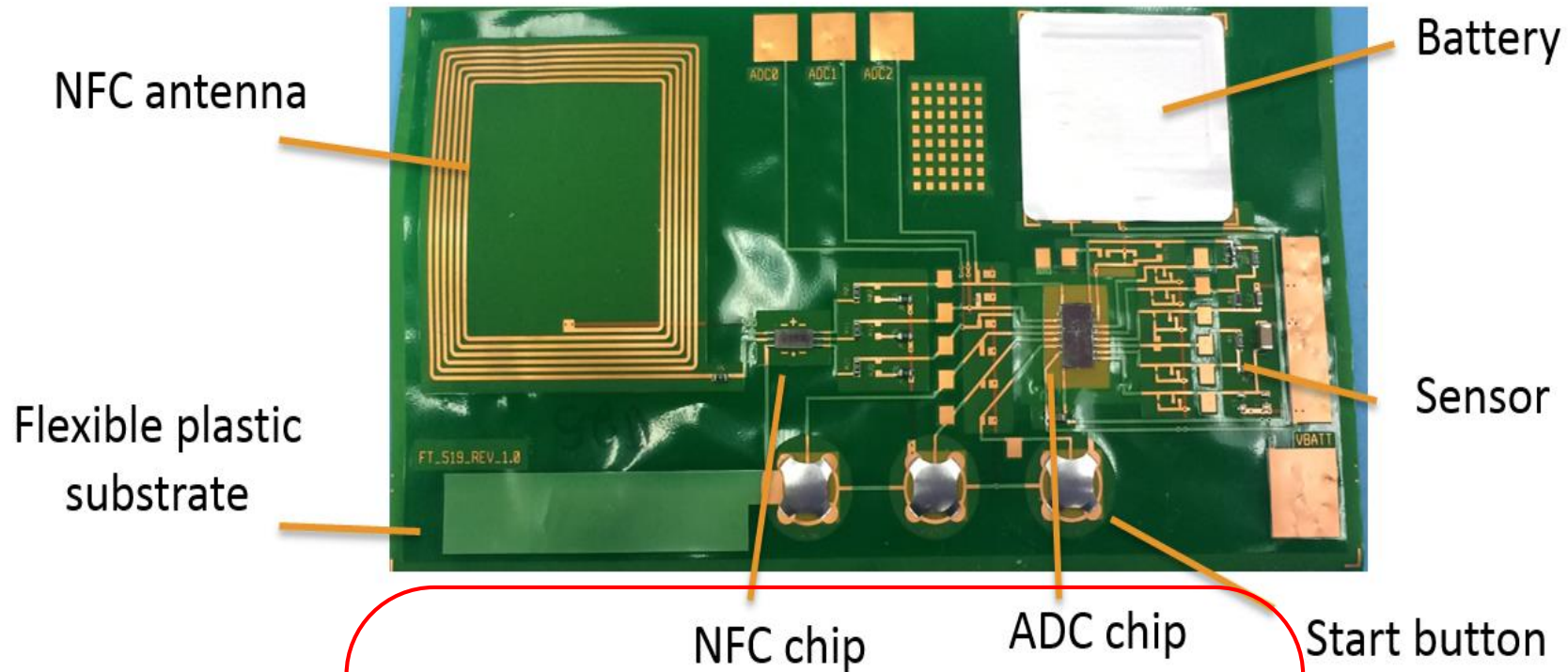
Volume Scaling to Low Cost with Roll Processing



Product Evolution with Sensors



Flexible NFC Sensor Label: 3 Bit ADC + NFC Readout



CMOS TFT on Stainless Steel

NFC Label Types: Common Sensor Platform

TEMPERATURE SENSOR LABEL

- Sensor: Resistive Thermistor
- Temperature Range :15°C-25°C
- Accuracy = +/-1.25°C

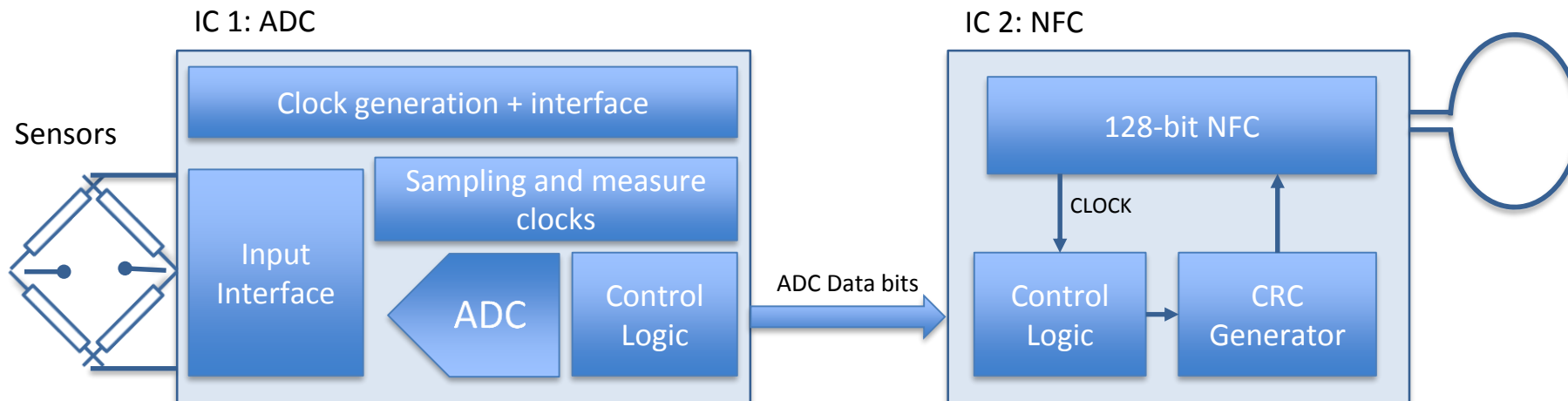
HUMIDITY SENSOR LABEL

- Sensor: Capacitive
- Relative Humidity Range :10%-80%
- Accuracy = $\pm 10\%$

LIGHT SENSOR LABEL

- Sensor: Light (Current)
- Light Range: 200 – 800Lux
- Accuracy = $\pm 85\text{Lux}$

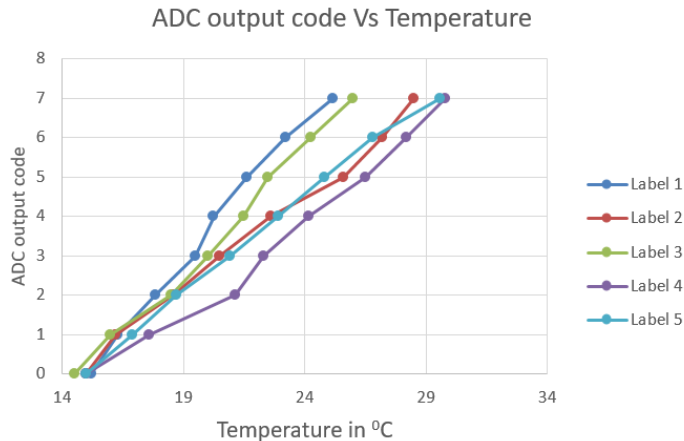
- Frequency variations from a reference generates 8 levels of ADC code.
- 8 unique NFC 128-bit data streams based on 3-bit ADC input



NFC Label Types: Sensor Data

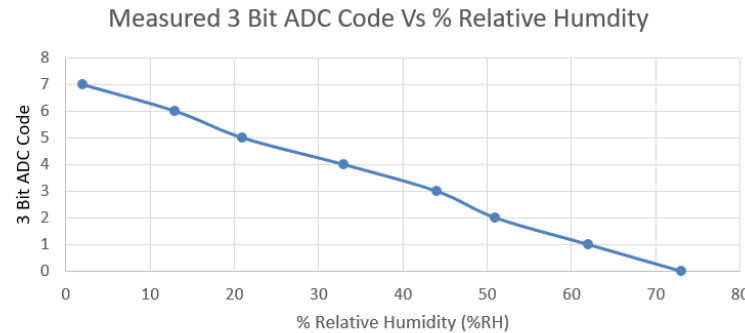
TEMPERATURE SENSOR LABEL

- Sensor: Resistive Thermistor
- Temperature Range :15°C-25°C
- Accuracy = +/-1.25°C



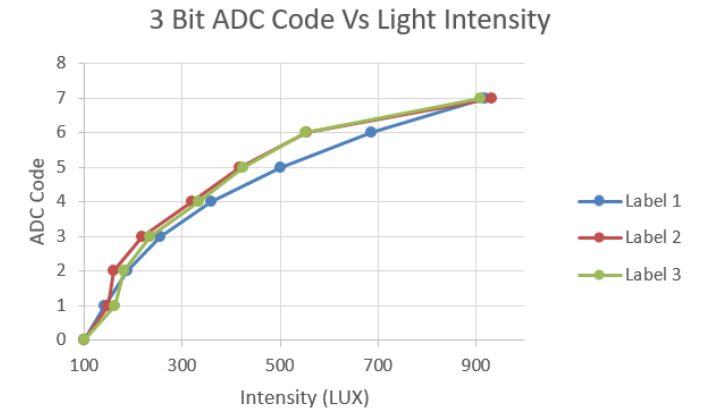
HUMIDITY SENSOR LABEL

- Sensor: Capacitive
- Relative Humidity Range :10%-80%
- Accuracy = $\pm 10\%$



LIGHT SENSOR LABEL

- Sensor: Light (Current)
- Light Range: 200 – 800Lux
- Accuracy = $\pm 85\text{Lux}$

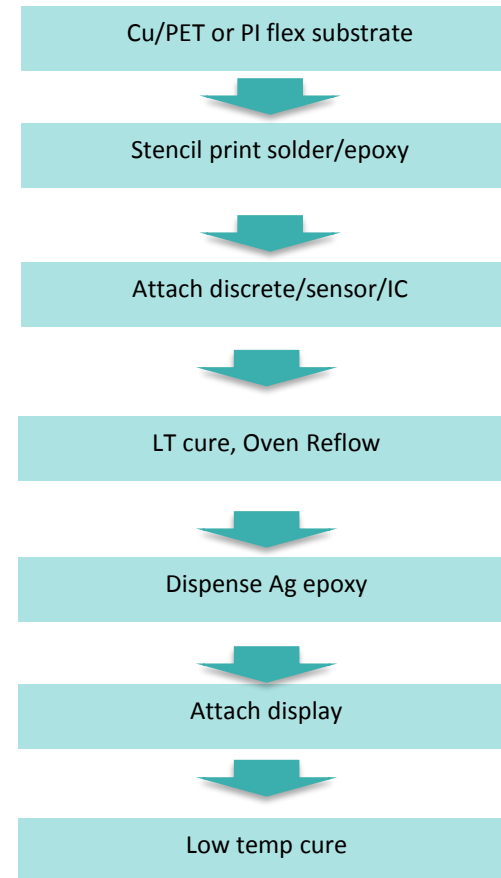
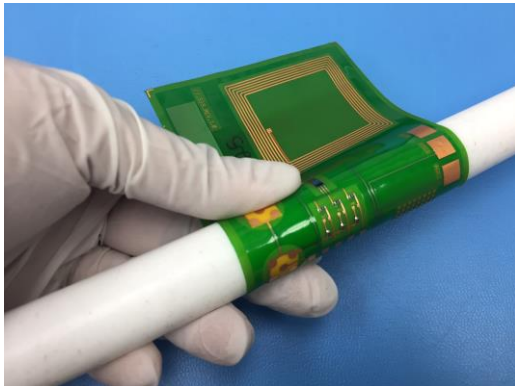


Low Temperature Flexible Label Assembly

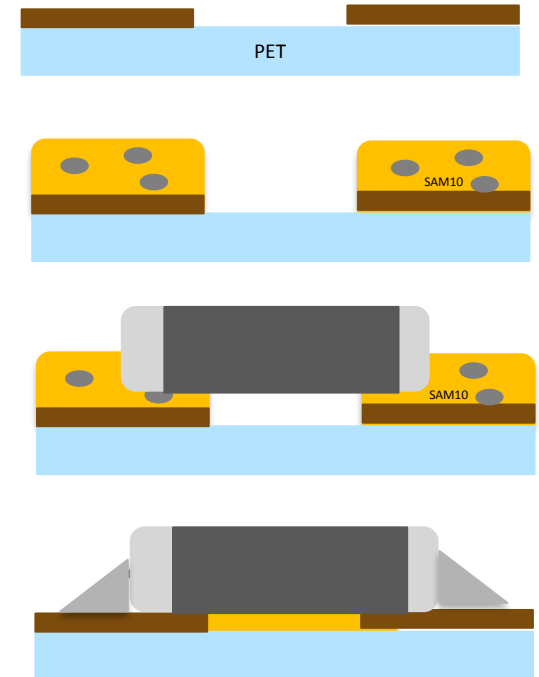
➤ A novel ink formulation of low temp solder and resin

➤ Key Points

- One step electrical and mechanical connection
- Self Aligned during Cure
- Minimal process steps
- PET Compatible assembly



LT Solder/Epoxy Phase separation



Thank You

www.thinfilm.no